HIGH QUALITY SURFACE PASSIVATION AND HETEROJUNCTION FABRICATION BY VHF-PECVD DEPOSITION OF a-Si:H ON c-Si THEORY AND EXPERIMENTS

Motivation

- ◆Reach high V_∞-high efficiency with a-Si:H/c-Si heterostructures: need of high quality c-Si surface passivation.
- •Investigation of a-Si:H layers passivation properties: analysis of lifetime measurements using an amphoteric model.
- Double side passivating layer structures speed up the development of high efficiency solar cell.

